



Patent

Attorney Docket No. 8003-398

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application)	<u>Patent Application</u>
)	
Inventor(s): Emir Gurer et al.)	Art Unit: 1763
)	
Application No: 09/874,073)	Examiner: Kackar, Ram N.
)	
Filed: June 4, 2001)	
)	
Title: Plasma Deposition of Spin Chucks to Reduce Contamination of Silicon Wafers)	
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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Introductory Comments:

This Amendment is in response to the Office Action dated December 31, 2002.
Reconsideration is respectfully requested in view of the following amendments and remarks.